



Attorney Docket No. 0756-7259

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Koichiro TANAKA et al.

Serial No. 10/787,120

Filed: February 27, 2004

For: LASER IRRADIATION METHOD,

LASER IRRADIATION APPARATUS,

AND METHOD FOR

MANUFACTURING

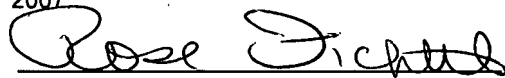
SEMICONDUCTOR DEVICE

) Group Art Unit: 2818

) Examiner: Chuong A. Luu

) CERTIFICATE OF MAILING

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) 2007

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AMENDMENT

Honorable Commissioner of Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated March 22, 2007, please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.